

Transmission electron forward scatter diffraction (t-EFSD)

- Is based on the **forward-dominance of low energy-loss scattering**.
- Detect and analyse transmitted electrons that have been **coherently forward scattered**
- Electrons that diffract **near the top surface cannot maintain coherence** for a significant distance in the specimen
- The most important **Kikuchi scattering occurs near the exit surface**

The **quality of the pattern** depends on both **specimen thickness and Acc. Voltage**

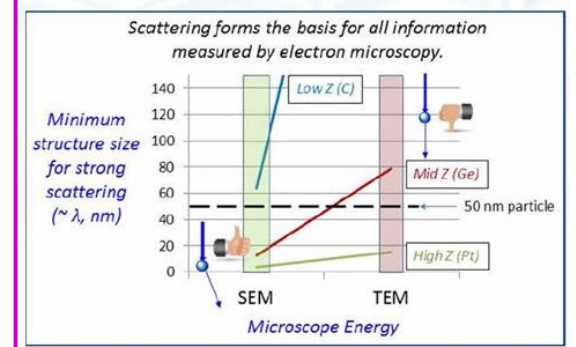
- Thicker samples pattern may also overlapping (Optimum between 75-200nm)
- ↓ KV - improve pattern in **thinner areas**, (maybe difficulties in indexing due to broader bands)

Angular resolution

- Standard conditions **0.5-1°** but it can be as good **0.003°** (strain measurements)
- **In thin samples** one must keep in mind the **artefacts** originating from the bending of the thin foil samples
- Because EBSD covers a **large enough solid angle** including a large number of zone axes, the **angular resolution is independent of the crystal orientation**.

Scattering mean free path (λ) = f(Z,E)

$\lambda \uparrow$ with E^2 and \downarrow with Z^2



When the size of the sample ↓ the λ must be decreases ↓ → go to **lower energy** will be beneficial (most relevant for mid and high atomic number nanoparticles).

Physical resolution = 6-8 nm
Effective resolution 2 nm (Nickel), ~10 nm (Al)

Specimen tilt

↓ tilt → **weaker band contrast** in the **upper part** of the detector → difficult for automated indexing → **Solution move the detector up**

↑ tilt → **electron beam path** in the specimen becomes **longer** → resulting in **increasing beam spreading and poor resolution**

Resolution depends on:

- Probe size – spatial resolution is in the order of the probe size
- Sample thickness – there is a range that works better (Ni:75-200nm; $t < 400/\rho$)
- Acceleration voltage – will depend on sample thickness and on Z
- Tilt angle – resolution in x and y direction and beam spread (also related to the pattern centre ↔ quality of indexing)
- Detector distance – compromise between large field of view and pattern shift accuracy (closer detector = zoom out)
- Working distance – shorter are better, but pattern centre outside the screen can cause indexing problems
- Atomic number Z – **Contrary to s-EBSD**, increasing Z increases beam broadening for a constant thickness and KV, and decrease resolution
- Number of grain through thickness – Some indications that does not affect much (???)

Better resolution

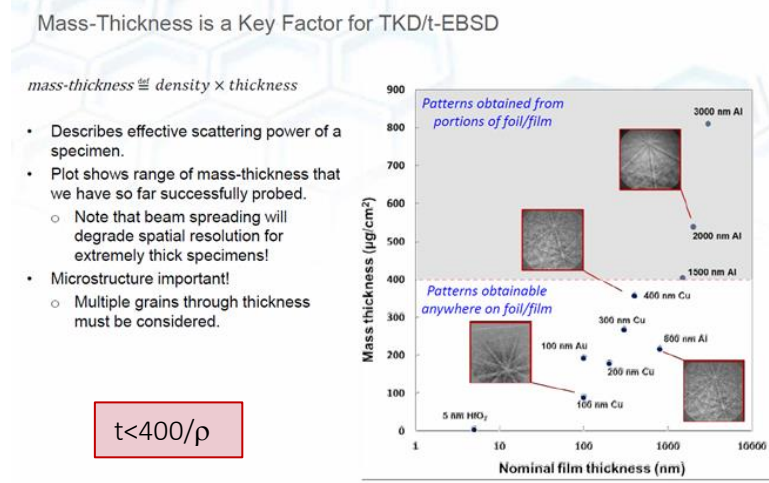
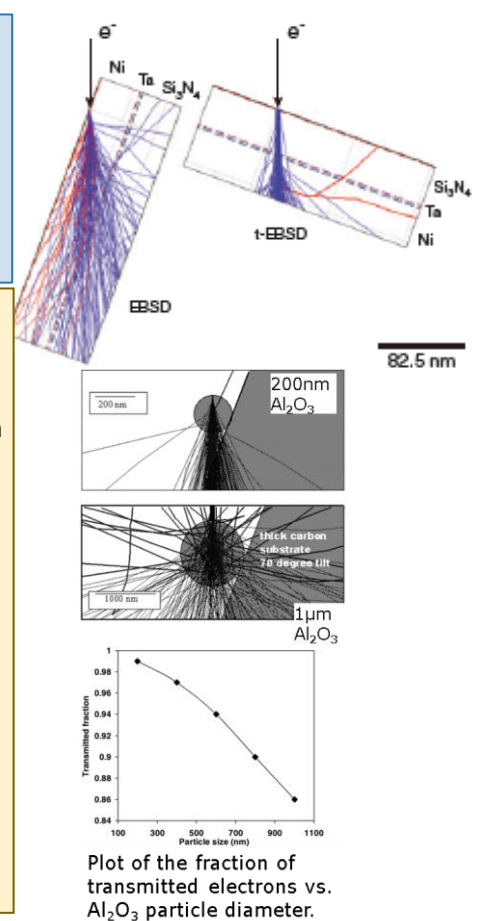
- Forward scattering is **favoured** → many electron my Kikuchi scatter near exit surface
- Forward scattered beam **scatter through small angles**.
 - Little beam spreading in thin specimens
 - Many high energy electrons reach the exit surface
 - Interaction volume is smaller

Parameters:

- Shorter detector sample distance (but not too short otherwise the camera resolution is not enough)
- Minimum tilt to avoid difference resolution in x and y direction
- Higher Acc. V is recommended to get **good quality orientation maps**.
- In case of **very thick samples**, lowering Acc.V will give better results

Typical parameters

- Tilt up to 30 degrees away from EBSD detector
- Short WD (pattern center on the screen) improve the lateral resolution
- Beam energy – 15-30KV
- Probe current – similar to EBSD (No study on this)
- Dwell time – similar to EBSD (our experience was a bit different)



T-EFSD general guideline

- Use the **TEM clamp holder** and put your sample in one of the extremities
- Fix the clamp holder to a cross-section stub in a way that your sample is far away from the stub
- Attach the cross-section stub to the pre-tilted EBSD stage on the longest side (the one that is tilted to 54°)
- Put the stage into the microscope and pump
- Bring your sample to a working distance of 3 mm (maybe 2.5 mm)
- Tilt stage to 36° to get the sample horizontal
- To improve orientation determination you can tilt the sample to -20° (stage tilt to 16°) – we have found that this was the optimum position.
- Change in OIM data collection software under setting/super users/ environment the environment setting to a specimen tilt of -20° (or whatever tilt you are using)
- Use the correct calibrated WD which are:

WD OIM	WD/ tilt Stage	WD/tilt sample
21	3mm/36°	3mm/0°
22	3mm/26°	3mm/-10°
23	3mm/16°	3mm/-20°

- Further step are just like regular EBSD, but better pattern are at 30KV
- The background is very critical for TKD, make sure you collect a background exactly from the area you are measuring or use dynamical background subtraction (take longer time)
- Remember to set the Environment Settings back to 70°

